orm PTO 1449	U.S. DEPARTMENT OF COMMERCE			ATTY DOCKET NO.		SERIAL NO.				
Modified)		PATENT AND TRAI	JEMARK OFFICE	292873US41PCT	10/584,052					
				APPLICANT						
LIST OF F	REFER	ENCES CITED BY AP	PLICANT	Stephane POCAS, et al.						
				FILING DATE		GROUP				
				June 22, 2006	2892					
				U.S. PATENT DOCUMENTS						
EXAMINER INITIAL		DOCUMENT NUMBER			CLASS	SUB CLASS	FILING DATE IF APPROPRIATE			
	AA	6,340,812	01/22/02	Yoshihiro IZUMI, et al						
	AB	2004/0097008 A1	05/2004	Glen J. LEEDY						
	AC	5,374,564	12/20/94	Michael BRUEL						
	AD	6,281,039	08/28/01	MARION						
	AF	2004/0014299	01/22/04	Hubert MORICEAU, et al.						
	AF	5,880,010	03/1999	Davison, HOWARD L.						
	AC	6,097,096	08/2000	GARDNER, et al.						
	AH	6,465,892	10/2002	SUGA, Tadatomo						
	Al	6,809,008	10/2004	HOLM, et al.						
	AJ	6,809,358	10/2004	HSIEH, et al.						
	AK	6,902,987	06/2005	TONG, et al.						
	AL	7,452,745	11/2008	DUPONT, et al.						
	AM	2002/0164839	11/2002	Paul M. ENQUIST						
	AN	2002/0173118	11/2002	DIETRICH, et al.						
	1		FC	DREIGN PATENT DOCUMENTS						
	·			The second secon		<u> </u>	TRANSLATION			
		DOCUMENT NUMBER	DATE	COUNTRY		YE	s NO			
	AO	2 783 969	03/31/00	France (equivalent of US 6, 281, 039)	elent of US 2004/0014299)		X			
	AP	2 816 445	05/10/02	France (equivalent of US 2004/001429			×			
	AQ	WO/2003/028101	04/2003	France (equivalent of US 2005/002002			X			
	AR	WO/01/18853 A1	03/2001	World Intellect (equivalent of US 7,208	3,392)	<u> </u>	×			
	AS									
	AT									
	AU									
	AV									
		OTHER	REFERENCES	(Including Author, Title, Date, Pertine	nt Pages,	etc.)				
	AW	QY. TONG, et al., INC., XP 008042464	"SEMICONDUC 1, pages 215-2	CTOR WAFER BONDING: SCIENCE AN 19, 1999.	D TECHN	OLOGY", J				
	AX	Goran THUNGSTROM, et al., "CONTACTS TO MONOCRYSTALLINE N - AND P- TYPE CILLICON BY WAFER BONDI USING COBALT DISILICIDE", Physica Scripta, Vol. T54, 1994, pages 77-80.								
	ISMAIL, M.S., et al., "PLATINUM SILICIDE FUSION BONDING", Electronics Letters, Vo. 27, No. 13, pages 1991.									
		PLOESSL, A., et al., "WAFER DIRECT BONDING: TAILORING ADHESION BETWEEN BRITTLE MATERIALS", Materials Science and Engineering, Vol. 25, No. 1-2, pages 1-88, 1999.								
	AZ	BETWEEN BRITTL	E MATERIALS	", Materials Science and Engineering, Vo	1. Ac	dditional Re	eferences sheet(s) attached			
Examiner	AZ	BETWEEN BRITTL	E MATERIALS	", Materials Science and Engineering, Vo		Iditional Re 	ferences sheet(s) attac			

Form PTO 1449		U.S. DEPARTMENT OF COMMERCE		ATTY DOCKET NO.		SERIAL NO.					
(Modified) PATENT AND TRADEMARK OFFICE			292873US41PCT	10/584,052							
				APPLICANT							
LIST OF	REFE	RENCES CITED BY AF	PLICANT	Stephane POCAS, et al.							
				FILING DATE		GROUP					
				June 22, 2006		2892					
				U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB FILING DATE IF APPROPRIATE					
	BA	2003/0129780	07/2003	Andre AUBERTON-HERVE							
	ВВ	2005/0020029	01/2005	JEAN-SEBASTIEN, Danel							
	ВС	2005/0104089	05/2005	ENGELMANN, et al.							
	BD	7,208,392 B1	04/2007	JAUSSAUD, et al.							
	BE	6,242,324 B1	06/2001	KUB, et al.							
	BF	2008/0041517	02/21/08	Hubert MORICEAU, et al.							
	BG	2008/0296712	12/04/08	Guy FEUILLET, et al.							
	ВН										
	ВІ										
	BJ										
4	вк										
	BL										
	вм										
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	BP										
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	ВР					,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,					
	BS										
	ВТ										
	BU										
	BV					· 					
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)											
	BW	SHIGETOU, A., et al., "ROOM TEMPERATURE BONDING OF ULTRA-FINE PITCH AND LOW-PROFILED CU ELECTRODES FOR BUMP-LESS INTERCONNECT", Electronic Components and Technology Conference, Vol. 53, pages 848-852, 2003.									
	вх	LJUNGBERG, K., et al., "BURIED COBALT SILICIDE LAYERS IN SILICON CREATED BY WAFER BONDING", Journal of the Electrochemical Society, Vol. 141, No. 10, pages 2829-2833, 1994.									
	BY	B. ASPAR, et al., "SMART-CUT PROCESS USING METALLIC BONDING: APPLICATION TO TRANSFER OF Si, GaAs, InP THIN FILMS", Electronics Letters, Vol. 35, No. 12, June 10, 1999, pages 1024-1025.									
	BZ			Additional References sheet(s) attached							
Examiner					Date Considered						
*Examiner: In conformance	itial if r	eference is considered, ot considered. Include c	whether or not opy of this form	citation is in conformance with MPEP 60 with next communication to applicant.	9; Draw lii	ne through	citation	if not in			